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This presentation is for

U Workshop 1 Big Data

X Workshop 3 Photonics and Micro-and-Nanoelectronics

□ Workshop 2 Robotics

Workshop 4 internet of Things



Description of the Organization





Description of the Organization Mission: Bringing Microelectronics into Application







Description of the your research interest







Photonic Interconnects for Data



Center

PhoxTroT, a EU flagship project, tackles optical interconnects in a holistic way, synergizing the different technology platforms in order to deploy the optimal "mix&match" technology and tailor this to each interconnect layer.



Tb/s Silicon Plasmonic Router





Pleros, N.; Vyrsokinos, K.; Papaioannou, S.; Fitsios, D.; Tsilipakos, O.; Pitilakis, A.; Kriezis, E.; Miliou, A.; Tekin, T.; Baus, M.; Karl, M.; Kalavrouziotis, D.; Giannoulis, I.; Avramopoulos, H.; Djellali, N.; Weeber, J.-C.; Markey, L.; Dereux, A.; Gosciniac, J.; Bozhevolnyi, S.; , "Tb/s switching fabrics for optical interconnects using heterointegration of plasmonics and silicon photonics: The FP7 PLATON approach," *IEEE Photonics Society, 2010 23rd Annual Meeting of the*, vol., no., pp.165-166, 7-11 Nov. 2010 doi: 10.1109/PHOTONICS.2010.5698810

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- Dense integration: ASIC with Silicon Photonics
- Embedded III-V laser sources on Silicon
- CMPOS compatible SiPh modulator
- Small cell size: <0.35mm2/channel
- 25Gbaud/channel



- Low-Power High integration with Lasers and EO modulators
- Low-Cost CMOS foundry / low cost assembly





TCTUR

Photonics KET 2017 - ICT-30-2017 **NG-PLATON NG-Phox**



- Objectives:
 - to develop new photonic technologies for metro and core networks allowing capacities of Pb/s per node, and Tb/s per channel and 100 Tb/s per link over increased transport distances, while supporting network programmability features and fitting network operator requirements and roadmaps.
 - to achieve major advances in chip integration technology, enabling a cost • effective volume manufacturing of PICs with significantly enhanced performances (e.g. integration complexity, footprint, energy efficiency, speed, ...) or new functions.
- Expected results
 - next generation agile, high-capacity and energy efficient core and metro networks to support the highly connected and communicating society;
 - Industrial volume manufacturing in Europe of PICs with significant competitive advantages in cost/performance and with reduced development ٠ costs:
 - New or significantly enhanced integration technology platforms for a more ٠ competitive Européan photonic industry.





No	Expertise	Туре	Country	Role in the project
01		RTD		
02		SME		
03		IND		
04				
05				
06				
07				
08				



FRAUNHOFER IZM Department WLSI



- R & D Activities
- Bulk- and Surface Micromachining (Anisotropic, Electrochemical Etching, DRIE)
- Microsensors (Pressure, Acceleration, Flow, Radiation, Gases)
- Microactuators (Printerheads, Micromotors, Microshutters, Micromirrors, Microswitches)
- High Temperature Sensors (SOI and SiC)
- **O** Smart Sensors
- **O** Materials Characterization
- Field Assisted and Fusion Bonding (Silicon/Pyrex- and Si/Si-Bonding)
- Modeling and Simulation (FEM-Simulation)



ICTURKE

Facilities and Equipment



- O Cleanrooms (1000 m², Class 1/10/1000, 100mm-300mm)
- **O** Basic Silicon Processes

(Oxidation, Annealing, LPCVD, PECVD, Sputtering, Photolithography, Wet and Dry Etching, Testing)

- Micromachining Laboratory (Anisotropic, Electrochemical Etching, DRIE)
- **O** Computer Controlled Testsystems for
 - Pressure Sensors, Accelerometers
 - •Temperature Sensors, Radiation Sensors
 - Humidity Sensors, Gassensors
- Computer Controlled Testsystems for (Si/Glass Bonding)
- PC based Workstations (FEM Simulation)
- O Analyses

(AFM, Raman, TEM, REM)







• MAT: Long experience in MEMS, development of microsensors and microactuators

• Physical and chemical microsensors: pressure, acceleration, flow ... gas concentration ...

Microactuators: inkjet heads, micromotors, micro relay, micro mirrors ...

• Further material research: gas sensitive materials, MEMS and sensor materials; development of process technology

• The future: New devices for power mems, micro optics, high temperature applications, aerodynamics research, gas sensing ...



Graphene based devices on a wafer-scale







- Graphene based sensors selective gas sensors
- Low-Power consumption ,Low-Cost and scaleable
- Possible to integrate into existing circuits
- A template with possibility to tailor for sensing of different gases
- Active in wide range of temperature and in harsh evironments





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Recommendations



- The presentation has to last up to 4 minutes (maximum)
- Do not overload your slides
- Provide weblinks to additional material
- Slides should be in English
- Do not use videos etc. they might be not supported by the Infoday IT system
- Send your presentation in PDF or PPTX format to: <u>ICT@turkeyinH2020.eu</u>
 <u>before November 21, 2016.</u>

